

Notice of References Cited	Application/Control No. 09/903,792	Applicant(s)/Patent Under Reexamination NAKATA ET AL.	
	Examiner Kripa Sagar	Art Unit 1756	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,346,564	02-2002	Kubota et al.	524/403
	B	US-2002/0076657	06-2002	Towata, Shuichi	430/322
	C	US-2002/0094382	07-2002	Imai et al.	427/282
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	"Thick Film Processes"; in Hybrid Microcircuit Technology Handbook, (Noyes, 1998), ch.4; pp. 104-171.
	V	
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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